

In re Application of:

Examiner:

Johnston, Phillip A.

David L. Adler, et al.

Serial No.

10/017,262

Art Unit:

2881

Filing Date:

12/14/2001

Attorney Docket No.: P960 (11.700)

Title:

Photoelectron Emission Microscope for Wafer and Reticle Inspection

Commissioner of Patents

P.O. Box 1450

Alexandria, Virginia 22313-1450

Sir:

This is responsive to the office action mailed on May 4, 2004. Note that this response is being filed within two months of the mailing date of the final action.